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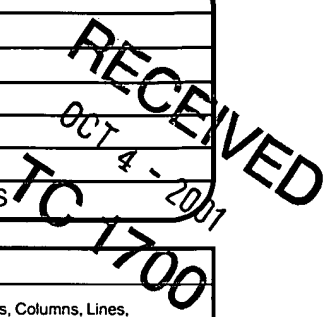
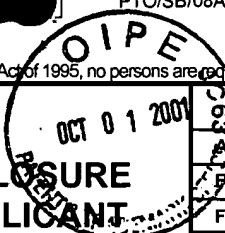
INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet 1 of 2

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Application Number 09/826,583
 Filing Date 04/06/01
 First Named Inventor Marc A. Unger
 Group Art Unit 1772
 Examiner Name Unassigned
 Attorney Docket Number 20174-003010US



U.S. PATENT DOCUMENTS

Examiner Initials *	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
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	3	5,876,187		Afromowitz et al.	03-02-1999	
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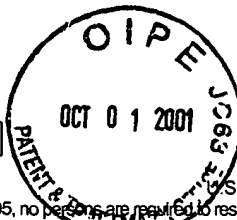
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Sheet 1 of 3

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Examiner Name	Unassigned
Attorney Docket Number	20174-003010US

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OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS

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